

METAL UNDERCOATING	INITIAL STRENGTH	TEMPERATURE ENVIRONMENT	HUMIDITY ENVIRONMENT	GOLD PLATING (CYANIDE GOLD PLATING SOLUTION)	ETCHING	REMARKS
Cu	○	×	×	×	○	
NiCr-BASED METAL	○	×	×	×	○	
NiV-BASED METAL	○	×	×	×	○	
Cr-BASED METAL	○	△	△	○	×	SPECIAL ETCHING ENVIRONMENT LOAD PRODUCTION OF HEXAVALENT CHROMIUM

FIG.1

FIG.2A

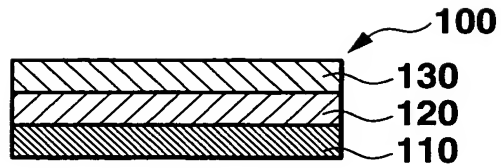


FIG.2B

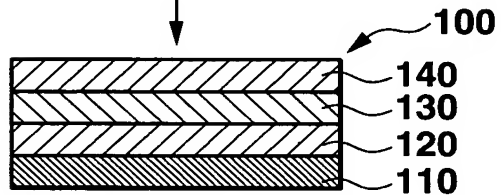


FIG.2C

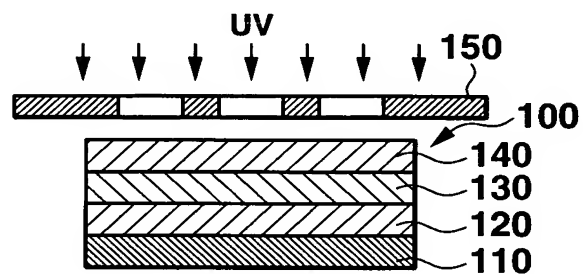


FIG.2D

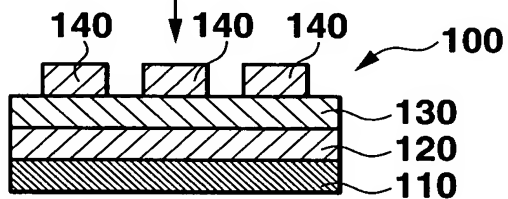


FIG.2E

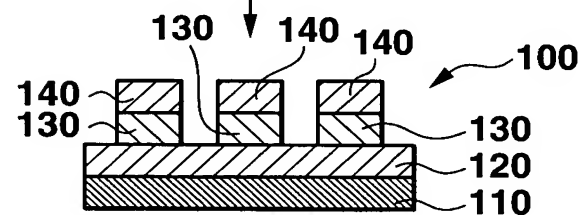


FIG.2F

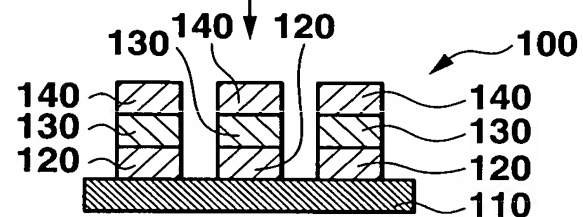


FIG.2G

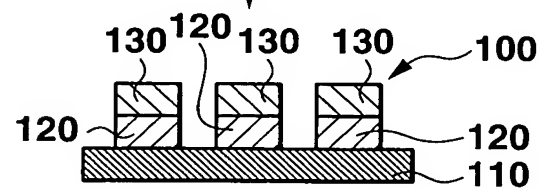


FIG.3A

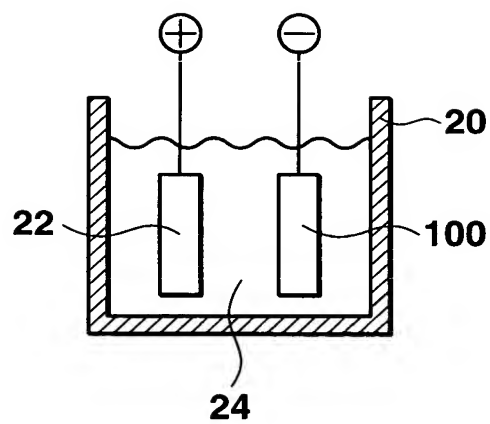


FIG.3B

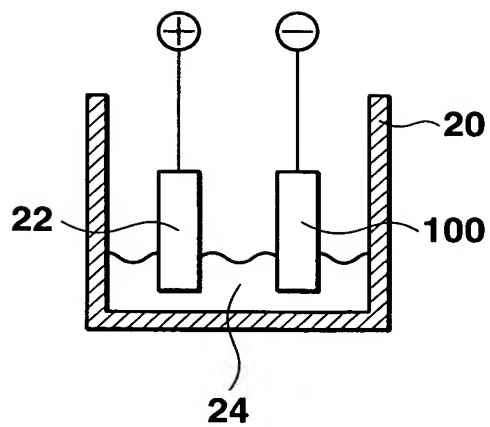
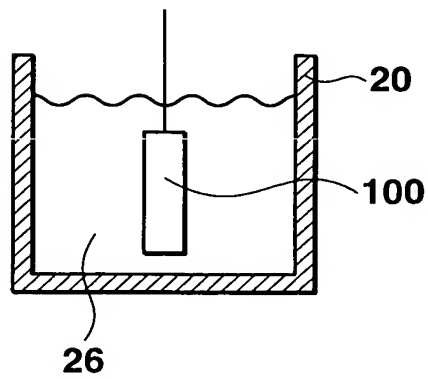


FIG.3C



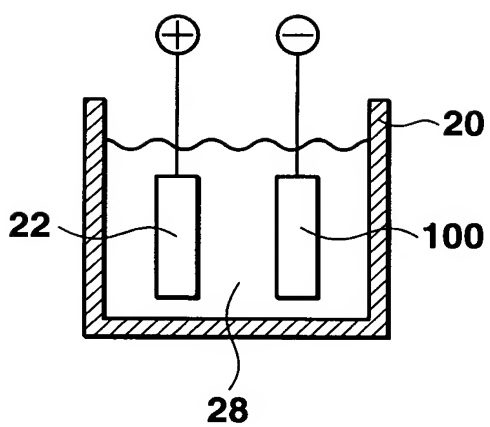


FIG.4

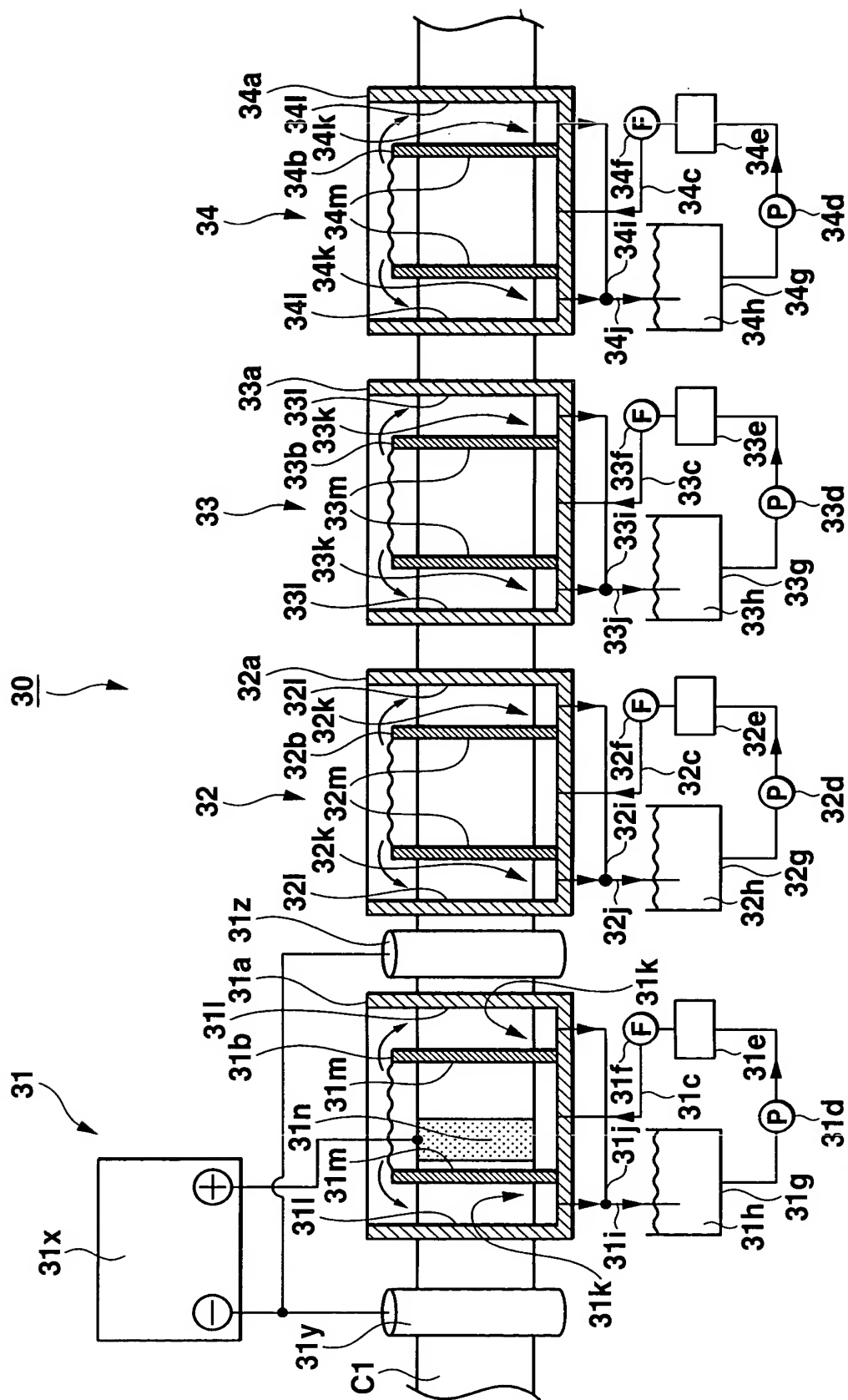


FIG.5

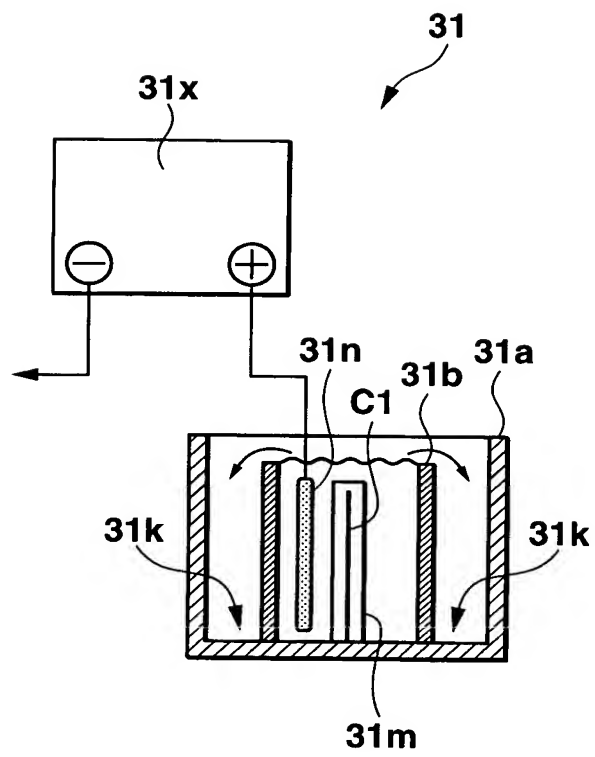


FIG.6

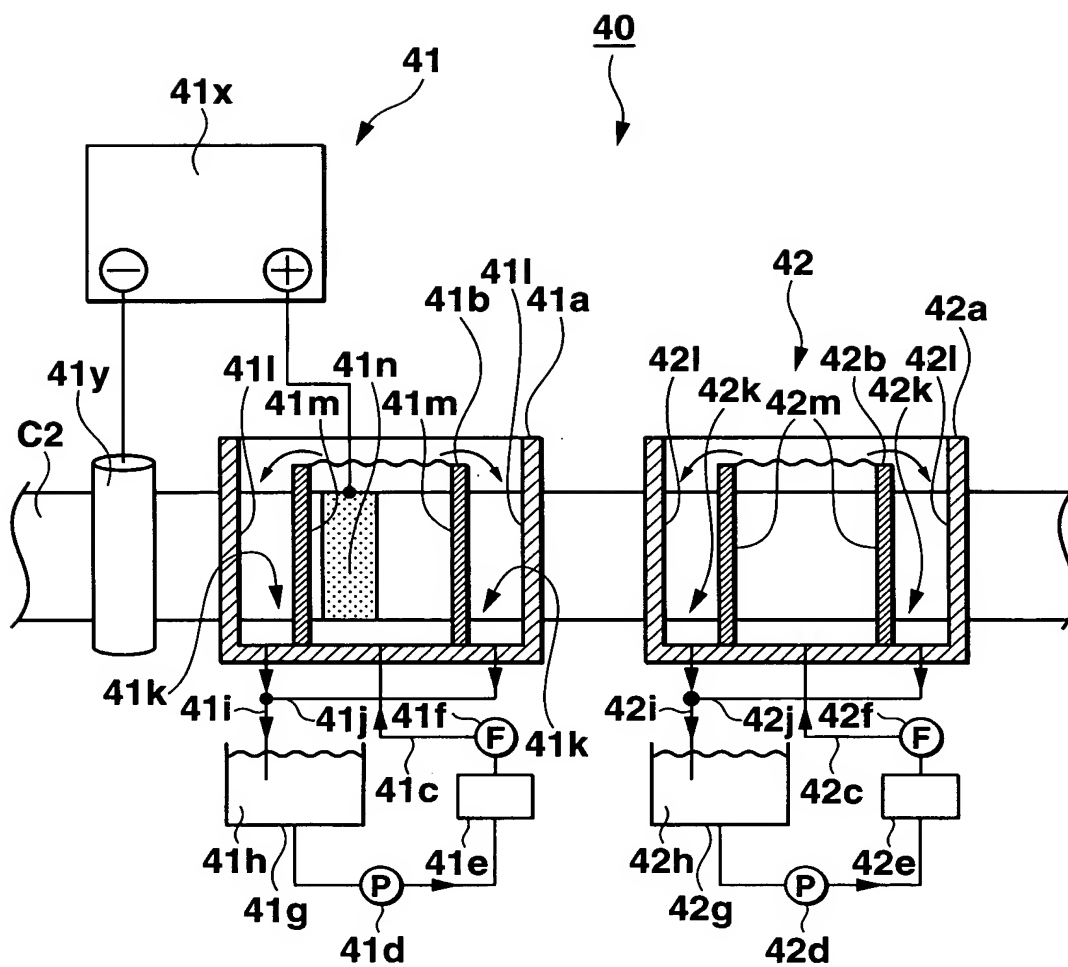


FIG.7

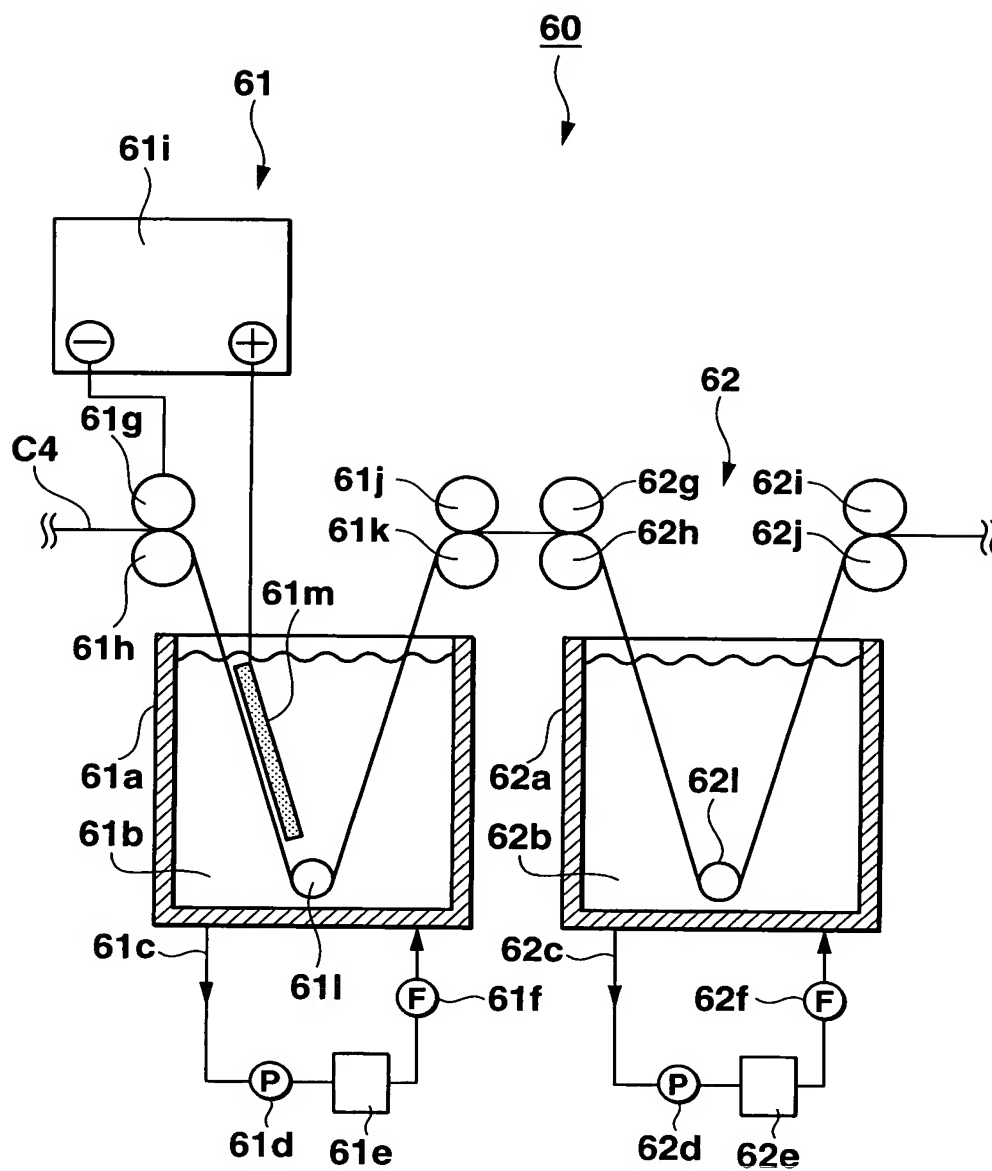


FIG.9

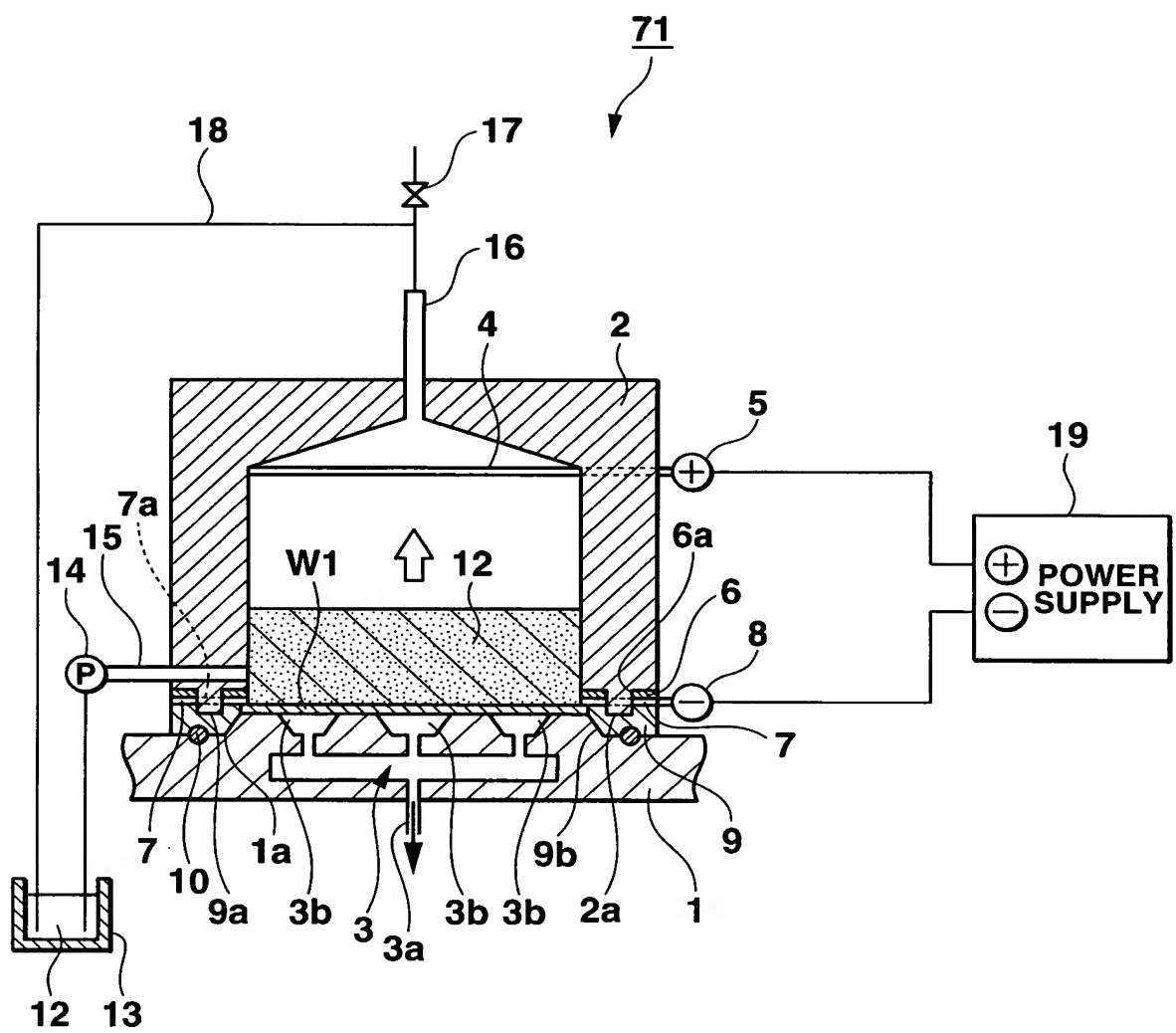


FIG.10

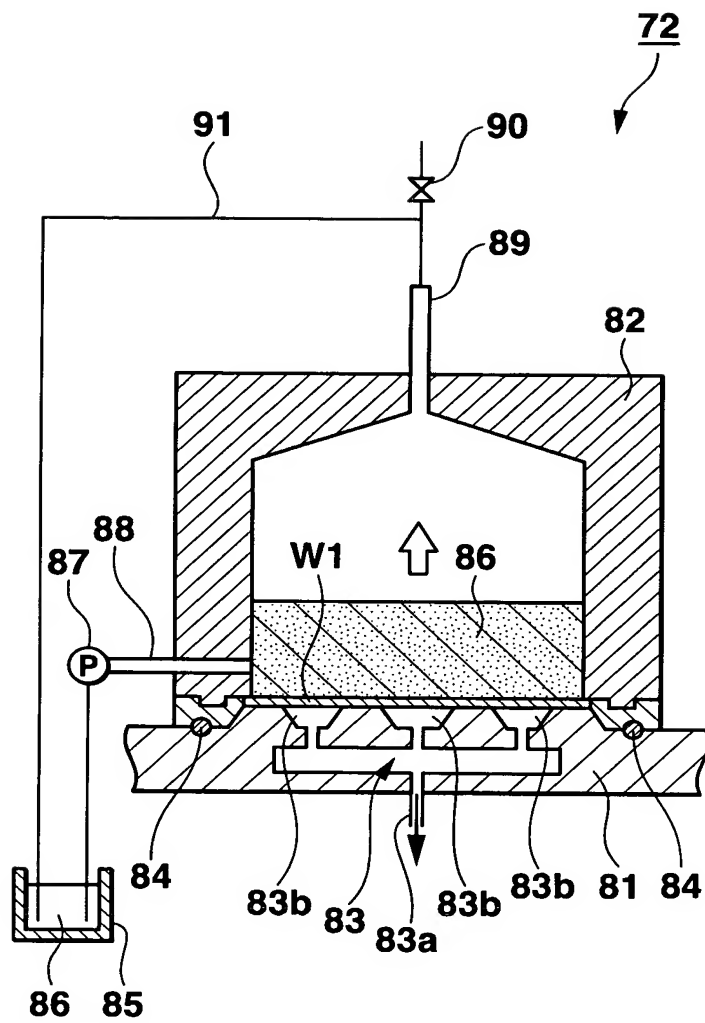


FIG.11

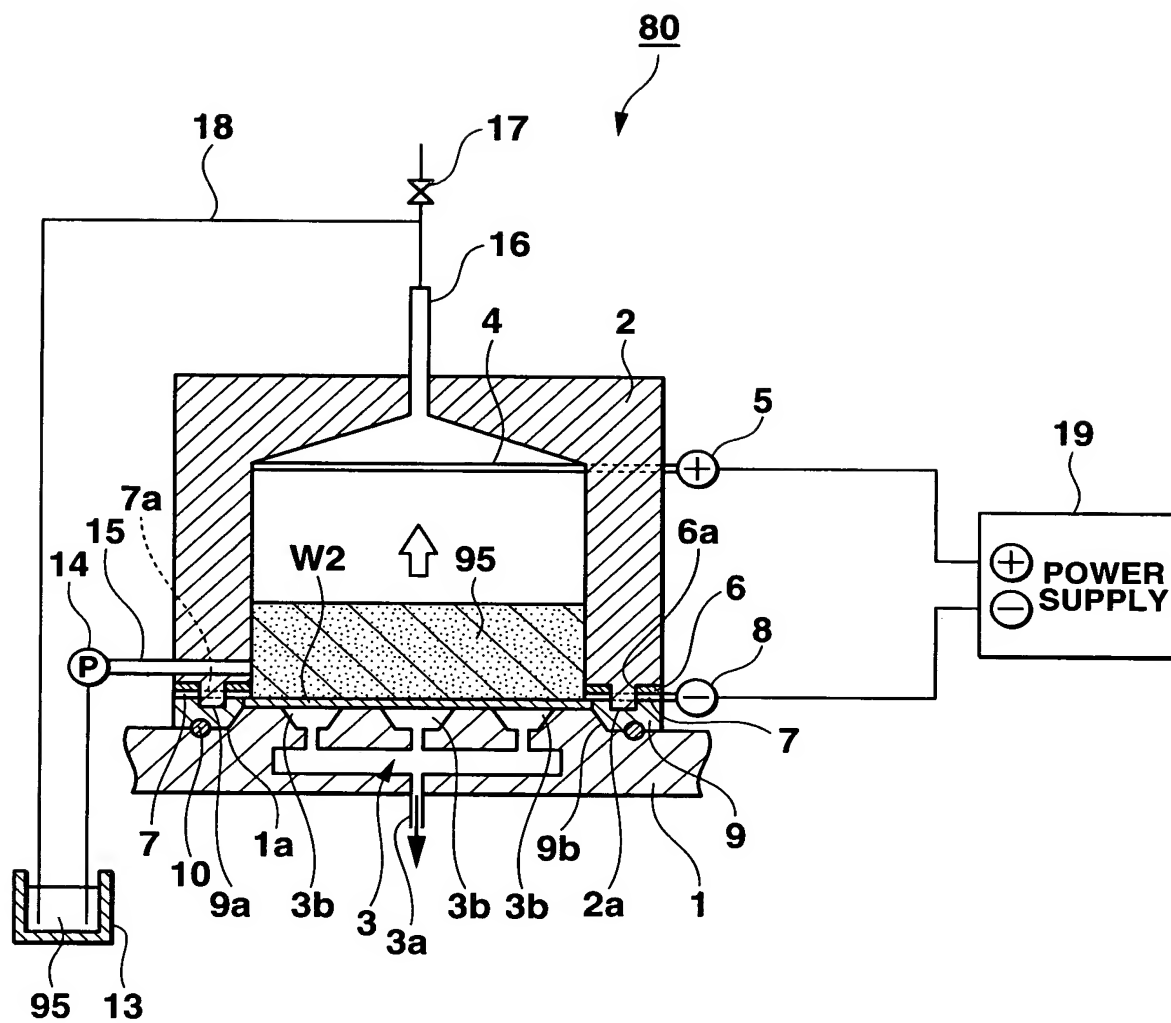


FIG.12

FORM	EXPERIMENT No.	PROPERTIES OF TREATMENT SOLUTION	NAMES OF TREATMENT SOLUTIONS	TREATMENT METHODS	TREATMENT SOLUTION CONCENTRATION (vol%)	ADDITIVE (REDUCING AGENT) CONCENTRATION (vol%)	CURRENT DENSITY (A/dm ²)	TEMPERATURE (°C)	TIME (sec)	Cu PEELING	Cr PEELING
SIMULTANEOUS (A)	1	ALKALINE	A-PROCESS (MANUFACTURED BY MELTEX K.K.)	DIP	100	50	25	○	×
									30	○	×
									90	○	×
INDIVIDUAL (B)	2	ACIDIC	CUPRIC CHLORIDE HYDROCHLORIC ACID	DIP	20~40	30	80	×	×
									85	○	×
	3	ACIDIC	SAS (MANUFACTURED BY K.K. MURATA)	DIP	50	30		...	×
										...	×
									30	...	×
									40	...	×
	4	ALKALINE	DSL-100 (MANUFACTURED BY K.K. MURATA)	ANODE ELECTROLYSIS OXIDATION	20	...	5	50	20	...	×
									30	...	×
	5	ACIDIC	SAS (MANUFACTURED BY K.K. MURATA)	CATHODE ELECTROLYSIS REDUCTION	50	...	5	30	10	...	×
									60	...	×
	6	ACIDIC	SAS (MANUFACTURED BY K.K. MURATA)	CATHODE ELECTROLYSIS REDUCTION	50	...	5	30	10	...	×
	7	ACIDIC	SAS (MANUFACTURED BY K.K. MURATA)	CATHODE ELECTROLYSIS REDUCTION+DIP	50/50	...	5/	30/30	2/8	...	○
									5/8	...	○
	8	ACIDIC+ REDUCING AGENT	SAS (MANUFACTURED BY K.K. MURATA) +SODIUM BISULFITE	DIP	50	0.1	...	30		...	×
						0.25				...	×
						0.5			30	...	×
						1				...	×

FIG.13

EXPERIMENT No.	PARAMETERS	SAS CATHODE ELECTROLYSIS REDUCTION TREATMENT CONDITIONS				SAS DIP TREATMENT CONDITIONS			Cr PEELING
		CONCENTRATION (vol%)	CURRENT DENSITY (A/dm ²)	TEMPERATURE (°C)	TIME (sec)	CONCENTRATION (vol%)	TEMPERATURE (°C)	TIME (sec)	
1	CURRENT DENSITY	50	1	30	2	50	30	17	○
2			5					10	
3	SAS CONCENTRATION IN DIP TREATMENT	50	1	30	2	5	30	22	○
4						10		20	
5						20		20	
6	SAS CONCENTRATION IN CATHODE ELECTROLYSIS REDUCTION TREATMENT	5	1	30	2	5	30	25	○
7		10				10		20	
8		20				20		20	

FIG.14

EXPERIMENT No.	TREATMENT METHODS	NaCl SOLUTION CATHODE ELECTROLYSIS REDUCTION TREATMENT CONDITIONS				SAS DIP TREATMENT CONDITIONS			Cr PEELING
		CONCENTRATION (wt%)	CURRENT DENSITY (A/dm ²)	TEMPERATURE (°C)	TIME (sec)	CONCENTRATION (vol%)	TEMPERATURE (°C)	TIME (sec)	
1	CATHODE ELECTROLYSIS REDUCTION USING NaCl SOLUTION	25	1	30	150	• • • •	• • • •	• • •	×
2	CATHODE ELECTROLYSIS REDUCTION USING NaCl SOLUTION+ DIP USING SAS	25	1	30	2	50	30	25	○

FIG.15

EXPERIMENT No.	CATHODE ELECTROLYSIS REDUCTION TREATMENT SOLUTION	DIP TREATMENT SOLUTION	Cr PEELING
1	NaCl (2N) (pH=5.1)	SAS	○
2	NaCl (2N)+NaOH (pH=7.0)	SAS	○
3	NaCl (2N)+NaOH (pH=9.0)	SAS	○
4	NaCl (2N)+NaOH (pH=10.0)	SAS	○
CONDITIONS	TEMPERATURE: ROOM TEMPERATURE	TEMPERATURE: ROOM TEMPERATURE	
	TIME: 30sec	TIME: 300sec	
	CD: 1A/dm ²	CONCENTRATION: 50%	
	ANODE: Pt		

FIG.16

TREATMENT SOLUTION	HYDROCHLORIC ACID		SULFURIC ACID		NaCl SOLUTION	
DIP TIME (sec)	1	5	1	5	1	5
CHROMIUM (D)	DETECTED	DETECTED	DETECTED	DETECTED	DETECTED	DETECTED
HEXAVALENT CHROMIUM	NOT DETECTED	NOT DETECTED	DETECTED	DETECTED	NOT DETECTED	NOT DETECTED

FIG.17